

SHORT BIO

Kristina Kutukova received her PhD from the Brandenburg University of Technology Cottbus-Senftenberg, Germany, in 2023. Her doctoral work, focusing on an "In-situ study of crack propagation in patterned structures of microchips using X-ray microscopy" earned her the DGM Young Scientist Award in 2023. Kristina Kutukova was a research associate in the Department of Microelectronic Materials and Nano-scale Analysis at Fraunhofer Institute for Ceramic Technologies and Systems Dresden, for more than 5 years. For several years, she was acting as Head of the Development and Application Lab at deepXscan GmbH, a start-up company, with the main tasks to the develop customized solutions for high-resolution 3D imaging and to coordinate development projects. In 2024, she expanded her knowledge of microelectronic products production and research by joining a Fraunhofer IZM, All Silicon System Integration Center Dresden (ASSID). Since September 2024 she took a role as Head of the Application X-ray in the PVA TePla in Dresden, dedicated to developing next generation of high-resolution X-ray microscopes for various areas of material metrology and defects inspection.